

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hiroki Nakamura et al.
Serial No.: 10/586,400
Filed: April 20, 2007
For: VACUUM DEPOSITION METHOD AND SEALED-TYPE
EVAPORATION SOURCE APPARATUS FOR VACUUM DEPOSITION
Art Unit: 1715
Examiner: Gambetta, Kelly M.
Att'y. Docket: 520514.00039
Confirmation No: 3841

Response to Restriction Requirement

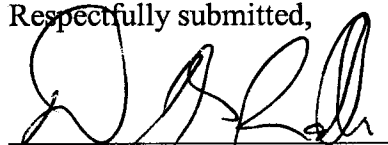
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to a restriction requirement in the Office Communication mailed on April 26, 2010 for the above application, Applicant elects claims 9-16 of Group 2 drawn to an evaporation source apparatus. Applicant reserves the right to file divisional applications containing the unelected claims.

No additional fees for filing this response are believed to be due. However, if such fees are due, the Commissioner is hereby authorized to charge them to deposit account no. 17-0055.

Respectfully submitted,



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